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Metal- and oxide-related hydrogen-induced dipoles at the Pt/HfO₂ interfaceN. M. Kolomiets¹, V. V. Afanas'ev¹, A. Stesmans¹, S. Fadida², M. Eizenberg²¹*Department of Physics and Astronomy, University of Leuven, Celestijnenlaan 200D, 3001 Leuven, Belgium*²*Department of Materials Engineering, Technion – Israel Institute of Technology, Haifa 32000, Israel**Corresponding author at: Department of Physics and Astronomy, University of Leuven, Celestijnenlaan 200D, bus 2417, B-3001 Leuven, Belgium. Tel.: +32 16 32 76 29. E-mail address: nadiia.kolomiets@kuleuven.be***Abstract**

Such technologically abundant agent as hydrogen has a strong effect on the metal/oxide interface energy barrier. Internal photoemission analysis of electron barrier height variations at Pt/HfO₂ interfaces caused by annealing in hydrogen reveals the formation of a significant (≥ 0.4 eV) electrostatic dipole layer. The orientation of the H-induced dipole appears to be sensitive to the growth conditions and treatments, e.g., Hf precursor used in the atomic layer deposition (ALD) process: In the case of the HfCl₄ precursor, annealing in H₂ leads to barrier lowering, whereas the barrier becomes higher in samples grown by using tetrakis(dimethylamido)hafnium. These findings indicate that hydrogen may form dipoles of opposite orientation through two different mechanisms: The positive dipole is caused by H interaction with the metal surface, which can also be found at interfaces of Pt with other oxides such as SiO₂ and Al₂O₃. By contrast, the sensitivity of the negative dipole formation to the HfO₂ ALD chemistry suggests it to be related to a negatively charged bonded state of hydrogen in the near-interface oxide. Moreover, the formation of positive dipole is also observed after high temperature anneal in nitrogen suggesting the contribution of additional mechanisms of dipole formation.

Keywords: Dipole; Internal Photoemission; Effective Work Function; Interface Barrier

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